


<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>				<b>Attorney Docket Number</b>	6333-67325
				<b>Application Number</b>	Not yet assigned
				<b>Filing Date</b>	Herewith
				<b>First Named Inventor</b>	Dickey
				<b>Art Unit</b>	Not yet assigned
				<b>Examiner Name</b>	Not yet assigned
<b>U.S. PATENT DOCUMENTS</b>					
<b>Examiner's Initials*</b>	<b>Cite No. (optional)</b>	<b>Number</b>	<b>Date</b>	<b>Name</b>	
N		4,058,430	11/15/77	Suntola et al.	
		4,389,973	6/28/83	Suntola et al.	
		5,091,320	2/25/92	Aspnes et al.	
		5,257,132	10/26/93	Ceglio et al.	
		5,321,713	6/14/94	Khan et al.	
		5,438,952	8/8/95	Otsuka	
		5,458,084	10/17/95	Thorne et al.	
		5,677,594	10/14/97	Sun et al.	
		5,711,811	1/27/98	Suntola et al.	
		5,712,528	1/27/98	Barrow et al.	
		5,785,756	7/28/98	Lee	
		5,804,919	9/8/98	Jacobsen et al.	
		5,872,655	2/16/99	Seddon et al.	
N		6,449,403	9/10/02	Cush et al.	

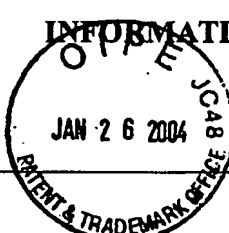
<b>EXAMINER SIGNATURE:</b> 	<b>DATE CONSIDERED:</b> 5-25-07
* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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				<b>First Named Inventor</b>	Dickey
				<b>Art Unit</b>	Not yet assigned
				<b>Examiner Name</b>	Not yet assigned
<b>FOREIGN PATENT DOCUMENTS</b>					
<b>Examiner's Initials*</b>	<b>Cite No. (optional)</b>	<b>Number</b>	<b>Date</b>	<b>Country</b>	
		<del>JP59045408</del>	<del>3/14/84</del>	<del>Japan</del>	
		<del>JP6196809</del>	<del>7/15/94</del>	<del>Japan</del>	
		<del>JP62002213</del>	<del>1/8/87</del>	<del>Japan</del>	
<b>Examiner's Initials*</b>	<b>Cite No. (optional)</b>	<b>OTHER DOCUMENTS</b>			
		T. Suntola, "Cost-effective Processing By Atomic Layer Epitaxy," <u>Thin Solid Films</u> , 225:96-98 (1993).			
		<del>T. Suntola, "Atomic Layer Epitaxy," <u>Thin Solid Films</u>, 216:84-89 (1992).</del>			

NOT PROVIDED BY APPLICANT.

Re

<b>EXAMINER SIGNATURE:</b>	<b>DATE CONSIDERED:</b>
* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.	

<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> 	<b>Attorney Docket Number</b>	6333-67325
	<b>Application Number</b>	10/713,362
	<b>Filing Date</b>	November 14, 2003
	<b>First Named Inventor</b>	Dickey et al.
	<b>Art Unit</b>	
	<b>Examiner Name</b>	

**U.S. PATENT DOCUMENTS**


Examiner's Initials*	Cite No. (optional)	Number	Date	Name
M		4,915,476	4-10-90	Hall et al
		5,102,694	4-7-92	Taylor et al.
		5,164,040	11-17-92	Eres et al.
		5,458,084	10-17-95	Thorne et al.
		5,472,505	12-5-95	Lee et al
		5,724,144	3-3-98	Muller et al.
N		5,916,365	6-29-99	Sherman

**FOREIGN PATENT PUBLICATION**

Examiner's Initials*	Cite No. (optional)	Number	Date	Country
M		0 416 251 A2	3-13-91	European
M		61018124	1-27-86	Japanese Abstract

**OTHER DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	
M		Kukli et al., "Real-Time Monitoring in Atomic Layer Deposition of TiO <sub>2</sub> from TiI <sub>4</sub> and H <sub>2</sub> O—H <sub>2</sub> O <sub>2</sub> " Langmuir 2000, 16: 8122-8128
M		Juppo et al., "In Situ Mass Spectrometry Study on Surface Reactions in Atomic Layer Deposition of Al <sub>2</sub> O <sub>3</sub> Thin Films from Trimethylalumin and Water", Langmuir 2000, 16, 4034-4039
M		Aarik et al., "Anomalous effect of temperature on atomic layer deposition of titanium dioxide", Journal of Crystal Growth 220 (2000) 531-537

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